Software (Standard)	SBH EasyProbe/SBH	SBU EasyProbe/SBU	LMH/XMH/GMH	LMU/XMU/GMU
Image Processing	<b>♂</b> / <b>∀</b>	<b>☑</b> / <b>☑</b>	<b>V</b> / <b>V</b> / <b>V</b>	<b>Y</b> / <b>Y</b> / <b>Y</b>
Analysis & Measurement	<b>♂</b> / <b>♂</b>	<b>♂</b> / <b>∀</b>	<b>♂</b> / <b>∀</b> / <b>∀</b>	<b>♂</b> / <b>∀</b> / <b>∀</b>
Object Area	<b>♂</b> / <b>∀</b>	<b>∀</b> / <b>∀</b>	<b>Y</b> / <b>Y</b> / <b>Y</b>	<b>♂</b> / <b>∀</b> / <b>∀</b>
Hardness	<b>♂</b> / <b>∀</b>	<b>∀</b> / <b>∀</b>	<b>Y</b> / <b>Y</b> / <b>Y</b>	<b>♥</b> / <b>♥</b> / <b>♥</b>
Tolerance	☑ / ☑	☑ / ☑	<b>Y</b> / <b>Y</b> / <b>Y</b>	<b>♂</b> / <b>∀</b> / <b>∀</b>
Multi Image Calibrator	☑ / ☑	☑ / ☑	<b>♂</b> / <b>∀</b> / <b>∀</b>	☑ / ☑ / ☑
Switch-Off Timer	<b>♂</b> / <b>∀</b>	<b>∀</b> / <b>∀</b>	<b>Y</b> / <b>Y</b> / <b>Y</b>	<b>♥</b> / <b>♥</b> / <b>♥</b>
3D Scanning	<b>♂</b> / <b>∀</b>	<b>∀</b> / <b>∀</b>	<b>Y</b> / <b>Y</b> / <b>Y</b>	<b>♥</b> / <b>♥</b> / <b>♥</b>
X-Positioner <sup>1</sup>	<b>0</b> / <b>\subset</b>	<b>0</b> / <b>S</b>	<b>Y</b> / <b>Y</b> / <b>Y</b>	<b>♥</b> / <b>♥</b> / <b>♥</b>
EasySEM™	☑ / ☑	☑ / ☑	<b>Y</b> / <b>Y</b> / <b>Y</b>	<b>♂</b> / <b>∀</b> / <b>∀</b>
Live Video	☑ / ☑	☑ / ☑	<b>Y</b> / <b>Y</b> / <b>Y</b>	<b>♂</b> / <b>∀</b> / <b>∀</b>
Histogram	☑ / ☑	☑ / ☑	<b>♂</b> / <b>∀</b> / <b>∀</b>	☑/☑/☑
Easy EDX Integration Software	☑ / ☑	☑ / ☑	0/0/0	0/0/0

Software (Optional)	SBH EasyProbe/SBH	SBU EasyProbe/SBU	LMH/XMH/GMH	LMU/XMU/GMU
Particles Basic	0/0	0/0	0/0/0	0/0/0
Particles Advanced <sup>1</sup>	<b>0</b> /□	<b>0</b> /□	0/0/0	0/0/0
Image Snapper <sup>1</sup>	<b>0</b> /□	<b>0</b> /□	0/0/0	0/0/0
DrawBeam Basic	<b>0</b> /□	<b>0</b> /□	0/0/0	0/0/0
DrawBeam Advanced	<b>0</b> /□	<b>0</b> /□	0/0/0	0/0/0
Sample Observer	0/0	0/0	0/0/0	0/0/0
System Examiner	0/0	0/0	0/0/0	0/0/0
TESCAN TRACE GSR <sup>1</sup>	<b>0</b> /□	<b>0</b> /□	0/0/0	0/0/0
EasyEDX Integration Software	☑/□	☑/□	0/0/0	0/0/0
3D Metrology (MeX)	0/0	0/0	0/0/0	0/0/0
Cell Counter	<b>0</b> /□	<b>0</b> /□	0/0/0	0/0/0
Coral	<b>0</b> /□	<b>0</b> /□	0/0/0	0/0/0
SYNOPSYS Avalon™	0/0	0/0	0/0/0	0/0/0

☑ standard, ☐ option, – not available, ¹ Only possible with optional position readout stage for SB chamber

### User-Friendly Software

- Multi-user environment localized in different languages
- Easy control of the SEM even for inexperienced users; four levels of user expertise/rights, including an EasySEM™ mode for quick routine investigations
- Image management and report creation
- Built-in self-diagnostics for system readiness checks
- Network operations and remote access/ diagnostics

### Software Tools

Modular software architecture enables several extensions to be attached.



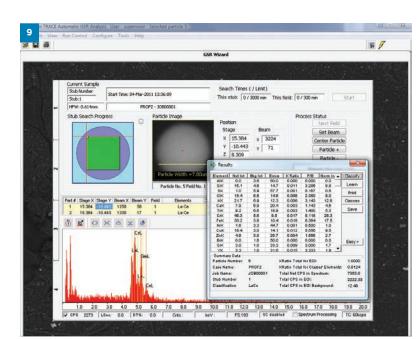


Fig. 9: Screenshot showing TESCAN TRACE GSR module.

## ■ Fast and Easy Way to Results

The intuitive EasySEM™ touch screen control interface enables rapid sample examination within minutes. A high level of system automation and self-diagnostics, running in the background, ensure valuable results even for inexperienced users. Optional fully integrated EasyEDX microanalysis brings quantitative elemental analysis results directly into the live SEM image with only one touch. Point and area analysis as well as quantitative line profile and array mapping (up to 1024 points) functions are available.

Tungsten heated cathode  3 nm at 30 keV 8 nm at 3 keV 3.5 nm at 30 keV  < 9 × 10 <sup>-3</sup> Pa <sup>2</sup>	Tungsten heated cathode / optionally LaB <sub>6</sub> 3 nm at 30 keV / 2 nm at 30 keV <sup>1</sup> 8 nm at 3 keV / 5 nm at 3 keV <sup>1</sup> 3.5 nm at 30 keV / 2.5 nm at 30 keV <sup>1</sup>		
8 nm at 3 keV 3.5 nm at 30 keV < 9 × 10 <sup>-3</sup> Pa <sup>2</sup>	8 nm at 3 keV / 5 nm at 3 keV <sup>1</sup>		
8 nm at 3 keV 3.5 nm at 30 keV < 9 × 10 <sup>-3</sup> Pa <sup>2</sup>	8 nm at 3 keV / 5 nm at 3 keV <sup>1</sup>		
< 9 × 10 <sup>-3</sup> Pa <sup>2</sup>	3.5 nm at 30 keV / 2.5 nm at 30 keV <sup>1</sup>		
2 150 D-	< 9 × 10 <sup>-3</sup> Pa <sup>2</sup>		
3 – 150 Pa	3 – 150 Pa		
3 – 500 Pa⁵	3 – 500 Pa <sup>5</sup> (optionally: 3 – 2000 Pa <sup>5</sup> )		
< 9 × 10 <sup>-3</sup> Pa <sup>2</sup>	< 9 × 10 <sup>-3</sup> Pa <sup>2</sup>		
	< 3 × 10 <sup>-5</sup> Pa		
3 × – 1,000,000 ×	2 × - 1,000,000 × (LM), 1 × - 1,000,000 × (XM/Gi		
Resolution, Depth, Field, Wide Field, Channelling			
Resolution, Depth			
7.7 mm at WD <sub>analytical</sub> 10 mm			
24 mm at WD 30 mm			
200 eV to 30 keV			
1 pA to 2 μA			
From 20 ns to 10 ms per pixel adjustable in steps or continuously			
tilted or folded plane up to ± 70 de compensation, 3D Beam – defined	osition continuously adjustable), Dynamic Focus – in plan eg, Point & Line Scan, Image rotation, Image shift, Tilt d tilting scanning axis around XY axis, Life Stereoscopic available through the optional DrawBeam software		
16,384 ×16,384 pixels, adjustable separately for live image (in 3 steps) and for stored image (11 steps), selectable square or 4:3 or 2:1 rectangle. Unlimited large panorama image size (1 to storage capacity).			
	trolled by keyboard, mouse and trackball via the progra n. Control panel and touchscreen optionally available.		
In-Flight Beam Tracing™ beam optimization, Spot Size a Beam Current Continual, WD (focus) & Stigmator, Contrast & Brightness, Scanning Speed (according to Signal- Noise Ratio), Gun Heating, Gun Centering, Column Centering, Vacuum Control, Compensation kV, Look-Up Table, Auto-diagnostics			
Via TCP/IP, open protocol			
	- 3 × - 1,000,000 × (for 5" image width in Continual V Resolution, Depth, Field, Wide Field Resolution, Depth  7.7 mm at WD <sub>analytical</sub> 10 mm 24 mm at WD 30 mm  200 eV to 30 keV  1 pA to 2 μA  From 20 ns to 10 ms per pixel adj Focus window (shape, size and potilited or folded plane up to ± 70 decompensation, 3D Beam – defined Imaging, Other scanning shapes at 16,384 ×16,384 pixels, adjustable s (11 steps), selectable square or 4.3 to storage capacity).  All microscope functions are contivegaTC using Windows™ platform  In-Flight Beam Tracing™ beam of (focus) & Stigmator, Contrast & Br Ratio), Gun Heating, Gun Centerink Look-Up Table, Auto-diagnosis		

available with LaB<sub>6</sub> option, <sup>5</sup> with a low vacuum aperture inserted



hone) +420 530 353 411 / (email) sales@tescan.cz / marketing@tescan.cz









## 3rd Generation of VEGA SEMs

VEGA3 is a versatile thermionic emission SEM system intended for both high- and low-vacuum operations designed with respect to a wide range of SEM applications and needs in today's research and industry. VEGA3 provides users with the advantages of the latest technology, such as new improved high-performance electronics for faster image acquisition, an ultra-fast scanning system with compensation for static and dynamic image aberrations or scripting for user-defined applications, all while maintaining the best price to performance ratio.

### ■ High Resolution Imaging with LaB, Emitter

TESCAN offers LaB (lanthanum hexaboride) electron source as an option. The LaB provides higher current density at lower cathode temperatures compared to tungsten emitters. It offers greater brightness, a reasonably improved resolution over the whole range of accelerating voltages and a longer cathode lifetime. The LaB emitter is the right choice for applications where large beam currents and improved resolution are required.

### Modern Optics

 A unique four-lens Wide Field Optics™ design with a proprietary Intermediate Lens (IML) offering a variety of working and displaying modes, for instance with enhanced field of view or depth of focus, etc.

- State-of-art design of the scanning coils and electronics enables an ultra-fast imaging rate down to 20 ns/pixel with minimized dynamic distortion effects.
- Real time In-Flight Beam Tracing™ for high precision real-time computation of optical parameters.
- · Column design without any mechanical centering elements enables fully automated column setup and alignment.
- Unique live stereoscopic imaging using advanced 3D Beam Technology opens up the micro and nano-world for an amazing 3D experience and 3D navigation.

### Analytical Potential

- The SB chamber is equipped with a 3-axis motorized stage, all other VEGA chambers (LM, XM and GM) provide superior specimen handling using a 5-axis fully motorized compucentric stage and ideal geometry for EDX and EBSD.
- First-class YAG scintillator-based detector.
- Selection of optional detectors and accessories.
- Full operating vacuum can be reached within a few minutes with powerful turbomolecular and rotary fore vakuum pumps.
- Investigation of non-conductive samples in the variable pressure mode (UniVac) version.
- Several chamber suspension type options ensure effective reduction of ambient vibrations in the laboratory.Unique integrated active vibration isolation for analytical GM chamber delivered as standard.
- · 3D measurements on a reconstructed surface by using the 3D metrology software.

### Rapid Maintenance

Keeping the microscope in peak condition is now easy and requires a minimum of microscope downtime. Every detail has been carefully designed to maximize microscope performance and minimize operator's efforts.

Automated Procedures Filament heating and alignment of the gun for optimal beam performance is performed automatically with just one click. There are many other procedures which reduce the time for tuning-up the microscope, including automated manipulator navigation and automated analyses. The SharkSEM remote control interface enables access to most of the microscope features, including microscope vacuum control, optics control, stage control, image acquisition, etc. The compact Python scripting library offers all these features.

# VEGA3 Configurations

### ■ VEGA3 SB

A high vacuum model of SEM with 3-axis motorized stage for investigation of small conductive samples.

### ■ VEGA3 SB – EasyProbe

The EasyProbe is a favorable package of a scanning electron microscope fully integrated with a selected EDX microanalyser. EasyProbe is available in both high vacuum and variable pressure variant. The system is delivered with a touch screen.

### ■ VEGA3 LMH / XMH / GMH

The large / extra-large / giantchamber models operate at high vacuum for the investigation of conductive samples with extraordinary imaging quality.

### ■ VEGA3 SBU / LMU / XMU / GMU

The variable-pressure SEMs supplement all the advantages of the high vacuum models with an extended facility for low vacuum operations, enabling the investigation of non-conductive specimens in their natural uncoated state.

The XM and GM configurations ex-

### About VEGA3 XM and GM configurations

tend their analytical capabilities, providing the ability to perform fine sample surface observations even with extra-large specimens. In today's microscopy there are many applications where breaking off a small piece of the sample is not possible or highly inconvenient. Particularly in situations where further analysis of the sample is needed. That is the case in forensic applications where the samples are usually valuable pieces of evidence. Besides the ability to investigate the sample surface with extra-large specimens, the GM chamber extends the features of VEGA3 SEMs with great analytical potential. A Large number of ports enables all detectors and techniques (SE, BSE, LVSTD, EDX, EBSD).

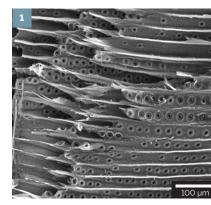


Fig. 1: Au-coated wood sample imaged at 20 keV

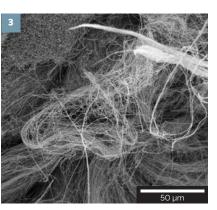
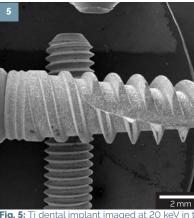
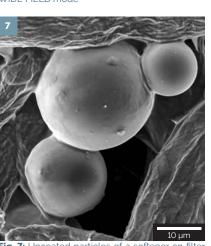
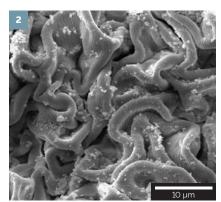


Fig. 3: Carbon nanotubes imaged at 5 keV







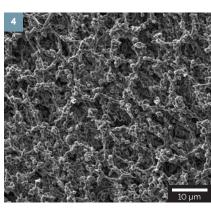
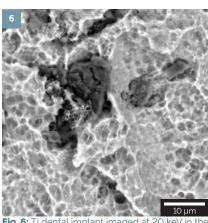
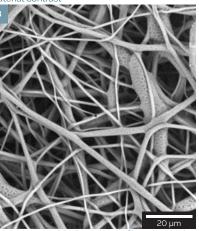


Fig. 4: Particles in a filter imaged at 5 keV





Low Vacuum Secondary Electron TESCAN Detector (LVSTD)<sup>2</sup>

**STEM Detector** 

CL Detector<sup>1,3</sup>

**BSE/CL Detector** 

EBIC

EDX<sup>4</sup> WDX<sup>4, 5</sup>

EBSD<sup>4</sup>

EasyEDX<sup>4</sup>

Rainbow CL Detector<sup>1,3</sup>

Al-coated BSE Detector<sup>1</sup>

HADF R-STEM Detector (motor.)

	SB Chamber	LM Chamber	XM Chamber		GM Ch	amber
Internal size	160 mm	230 mm	290 mm (w) × 340 r	nm (d)	340 mr	m (w) × 315 mm (d)
Door	120 mm (width)	148 mm (width)	290 mm (w) × 322 r	nm (h)	340 mr	n (w) × 320 mm (h)
Number of ports	10	11+	12+		20+	
Chamber and Column Suspension	Mechanical – by means of rubber elements	Pneumatic or optionally Mechanic (rubber elements - not available for LaB <sub>e</sub> option) Integrated active vibration isolation	Pneumatic or optio Integrated active vi isolation		Integra isolatio	ted active vibration
	Specimen stage in SB Chamber	Specimen stage in LM Chamber	Specimen stage in XM Chamber			men stage Chamber
Туре	eucentric 3-axis motor.	compucentric	compucentric		compi	ucentric
Movements	without / with position readout'  X = 45 / 35 mm - mot.  Y = 45 / 35 mm - mot.  Z = 27 / 27 mm - man.  Z' = 6 / 6 mm - man.  Rotation: 360°  Tilt: -90° to +90° - man.	X = 80 mm Y = 60 mm Z = 47 mm Rotation: 360° cont. Tilt: -80° to +80°	X = 130 mm Y = 130 mm Z = 100 mm Rotation: 360° con Tilt: -30° to +90°	t.		) mm
Max.Specimen height	36 / 34 mm	54 mm (with rotation stage) 81 mm (without rotation stage)			m (with rotation stage)	
*Not available for SB EasyPr	obe options	SBH EasyProbe/ SBH	SBU EasyProbe/ SBU	LMI- XMH/		LMU/ XMU/GMU
SE detector		<b>∀</b> / <b>∀</b>	<b>∀</b> / <b>∀</b>	<b>∀</b> / <b>∀</b>	/ 🗹	<b>Y</b> / <b>Y</b> / <b>Y</b>
Fixed BSE		<b>0</b> /□	<b>0</b> /□	0/0	/0	0/0/0
Retractable BSE Dete	ctor¹	0/0	☑ / ☑		1/0	<b>Y</b> / <b>Y</b> / <b>Y</b>
Retractable Dual Scin	tillator BSE Detector <sup>1</sup>	<b>0</b> /□	<b>Ø</b> /□		1/0	0/0/0
Retractable 4-Quadra	nt BSE Detector <sup>1</sup>	<b>Ø</b> /□	<b>Ø</b> /□		1/0	0/0/0

(N, conditions) / up to 1000 Pa (water vapour/N, conditions). Compact version available specially designed for simultaneous CL and BSE detection. Fully integrated third party products. Integrated active vibration isolation necessary.

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	SBH EasyProbe/ S	SBU EasvProbe/	LMH/	LMU/	
Accessories*	SBH	SBU	XMH/GMH	XMU/GMU	
oA Meter	☑ / ☑	☑ / ☑	<b>V</b> / <b>V</b> / <b>V</b>	<b>Y</b> / <b>Y</b> / <b>Y</b>	
Touch Alarm	☑ / ☑	☑ / ☑	<b>V</b> / <b>V</b> / <b>V</b>	<b>V</b> / <b>V</b> / <b>V</b>	
R TV Camera	0/0	0/0	<b>V</b> / <b>V</b> / <b>V</b>	<b>♂</b> / <b>∀</b> / <b>∀</b>	
Peltier Cooling Stage	0/0	0/0	0/0/0	0/0/0	
Water Vapor Inlet	0/0	0/0	0/0/0	0/0/0	
Beam Blanker for SEM column	0/0	0/0	0/0/0	0/0/0	
Load Lock"	0/0	0/0	0/0/0	0/0/0	
Control Panel	0/0	0/0	0/0/0	0/0/0	
Optical Stage Navigation	0/0	0/0	0/0/0	0/0/0	
Nanomanipulators	0/0	0/0	0/0/0	0/0/0	

**≤** standard, □ option, **⊘** not available,

combinations of optional detectors and other accessories must be discussed with TESCAN

Manual and motorised options available